

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Noriyuki SAKUMA et al.  
Appl. No.: **NEW NON-PROVISIONAL** Group:  
Filed: October 28, 2003 Examiner:  
For: WAFER POLISHING METHOD AND WAFER POLISHING  
APPARATUS IN SEMICONDUCTOR FABRICATION  
EQUIPMENT

INFORMATION DISCLOSURE STATEMENT  
(SUBMISSION CONCURRENT WITH THE  
FILING OF A NEW PATENT APPLICATION)

Assistant Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

October 28, 2003

Sir:

Pursuant to 37 C.F.R. §§ 1.97 and 1.98, and in fulfillment of the duty of disclosure under 37 C.F.R. § 1.56, applicant(s) hereby submit(s) an Information Disclosure Statement for consideration by the Examiner.

I. LIST OF PATENTS, PUBLICATIONS OR OTHER INFORMATION

The patents, publications, or other information submitted for consideration by the Office are listed on PTO-1449, attached hereto.

II. COPIES

- ☒ Submitted herewith is a legible copy of (i) each foreign patent; (ii) each publication or that portion which caused it to be listed; and (iii) all other information or that portion which caused it to be listed.
- ☐ This application is a National Phase of a PCT application. Some or all of the documents listed on the PTO-1449 are not enclosed because they were cited in the International Search Report and copies should have been forwarded from the International Search Authority pursuant to the trilateral agreement between the USPTO, EPO and JPO. If copies are needed, please contact the undersigned.

III. CONCISE EXPLANATION OF THE RELEVANCE  
(check at least one box)

- a. ☐ **DOCUMENTS IN THE ENGLISH LANGUAGE**

The attached patents, publications, or other information in the English language do not require a statement of relevancy.

b. ☒ **DOCUMENTS NOT IN THE ENGLISH LANGUAGE**

A concise explanation of the relevance of all patents, publications, or other information listed that is not in the English language is as follows:

Abstracts provided for the Examiner's convenience

c. ☐ **FOREIGN SEARCH REPORT OR ACTION**

An English language version of the search report or action that indicates the degree of relevance found by the foreign office is attached, thereby satisfying the requirement for a concise explanation. See MPEP 609(A)(3).

d. ☐ **OTHER**

The following additional information is provided for the Examiner's consideration.

**FEEs**

This Information Disclosure Statement is being filed concurrently with the filing of a new patent application; therefore, no fee is required.

If The Examiner has any questions concerning this IDS, he/she is requested to contact the undersigned.

Respectfully submitted,

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Enclosures: ☒ Form PTO-1449(s)  
☒ Documents  
☐ Foreign Search Report  
☐ Other: \_\_\_\_\_

<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>  (Use several sheets if necessary)	Attorney Docket No.: <b>8017-1104</b>	Application No.: <b>NEW NONPROVISIONAL</b>
	Applicant: <b>Noriyuki SAKUMA et al.</b>	
	Filing Date: <b>October 28, 2003</b>	Group Art Unit:

### U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing date (if appropriate)

### FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	2000-117615	4/25/2003	JAPAN			*	
	2002-086342	3/26/2002	JAPAN			*	
	2001-252859	9/18/2001	JAPAN			*	
	2000-202758	7/25/2000	JAPAN			*	

### OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)


EXAMINER:	DATE CONSIDERED
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

\* Abstract provided for the Examiner's convenience

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